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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/361,980  
Filing Date: July 28, 1999  
Applicant: Yasuaki Tsuzuki et al.  
Group Art Unit: 1765  
Examiner: Lynette T. Umez-Eronini  
Title: Method of Etching Metallic Thin Film on Thin Film Resistor  
Attorney Docket: 4041J-000439

E/A  
L.T.U-E,  
6/19/03

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Director of the United States Patent and Trademark Office  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action mailed February 26, 2003, Paper No. 19, please amend and reconsider the above-referenced patent application as follows.

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 7 of this paper.